

# Enhanced Quantum Efficiency of Photocathodes with Polarized Emission

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in collaboration with  
Matt Poelker, Jefferson Lab (JLab):

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# Outline

- Company introduction
- Photocathodes
- Molecular Beam Epitaxy
- GaAsP/GaAs Superlattice Photocathode
- Our approach: extending operational characteristics of photocathodes by adding integrated mirrors
- Conclusion

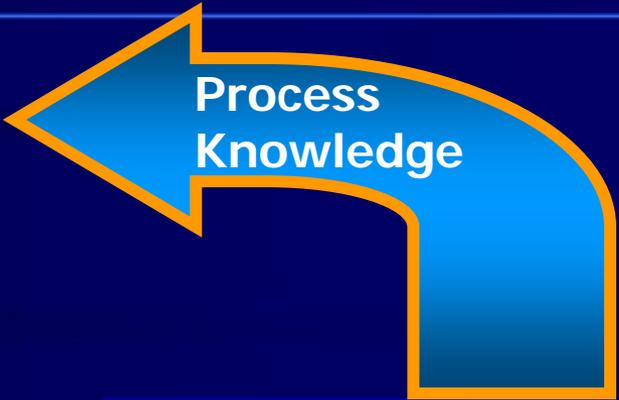


# SVT Associates, Inc. Company Overview

- **Located in Eden Prairie, MN (Minneapolis Metro Area)**
- **Founded in 1993 as MBE equipment provider**
- **35 employees**
- **Currently supplies vacuum processing modules for MBE and other thin films deposition (e.g. CIGS)**
- **SVTA's applications laboratory conducts R&D into materials, supplies epi-wafers and devices, test and develops hardware**
- **One of today's leading suppliers with > 120 systems in the field**



# SVTA Product Line ([www.svta.com](http://www.svta.com))

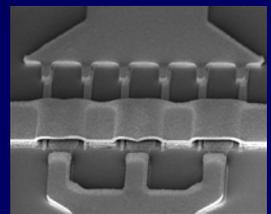
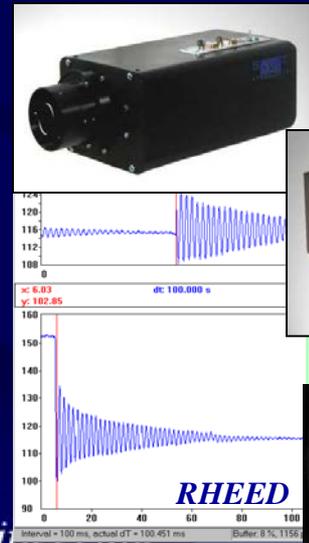


MBE Systems  
and  
Components

ALD, PLD  
UHV Deposition

In-situ Process  
Monitoring  
& Control

Applications Lab  
MBE Growth  
& Devices Fab.



SVTA-UV-C Solar-Blind  
Detector



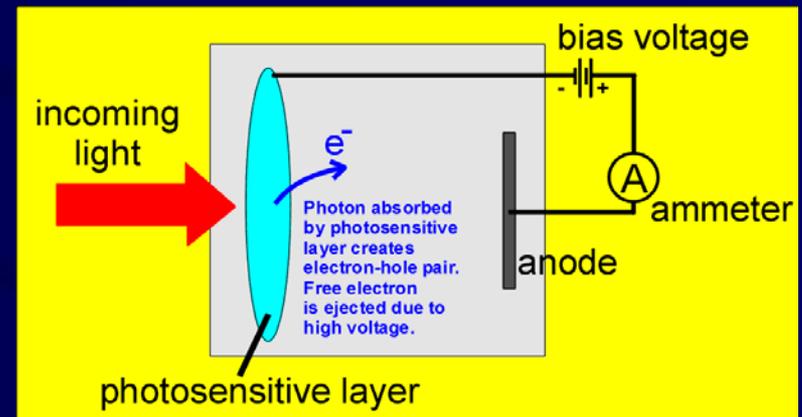
# Semiconductors Research at SVT

- **US Government and Industrial research grants**
- **Established research collaboration with many universities: Illinois, North Carolina State, Florida, Stanford ...**
- **Highly technically oriented, PhD scientists & engineers**
- **> 100 book chapters, publications and presentations**
- **Significant Antimonide, Nitride and ZnO accomplishments**
  - **High power HEMT & MOSHEMT**
  - **Commercialized solar blind UV detector products**
  - **High efficiency photocathode**
  - **Innovative LED utilizing Quantum Structures**
  - **New mid Infrared Laser and LWIR Photodiode**
  - **Rainbow colored MgZnCdO**

# Photocathodes

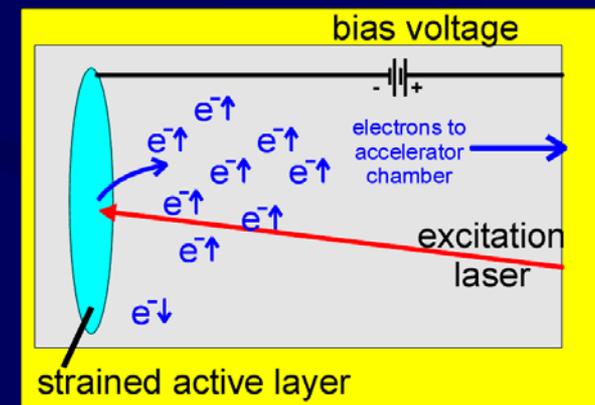
- *Photocathodes for conversion of light into electron current*
  - *Electrons and holes created by photon absorption*
  - *Electrons ejected due to applied high voltage*
  - *Electron current captured or reabsorbed by phosphor*

*Basic Photocathode Operation (transmissive mode)*



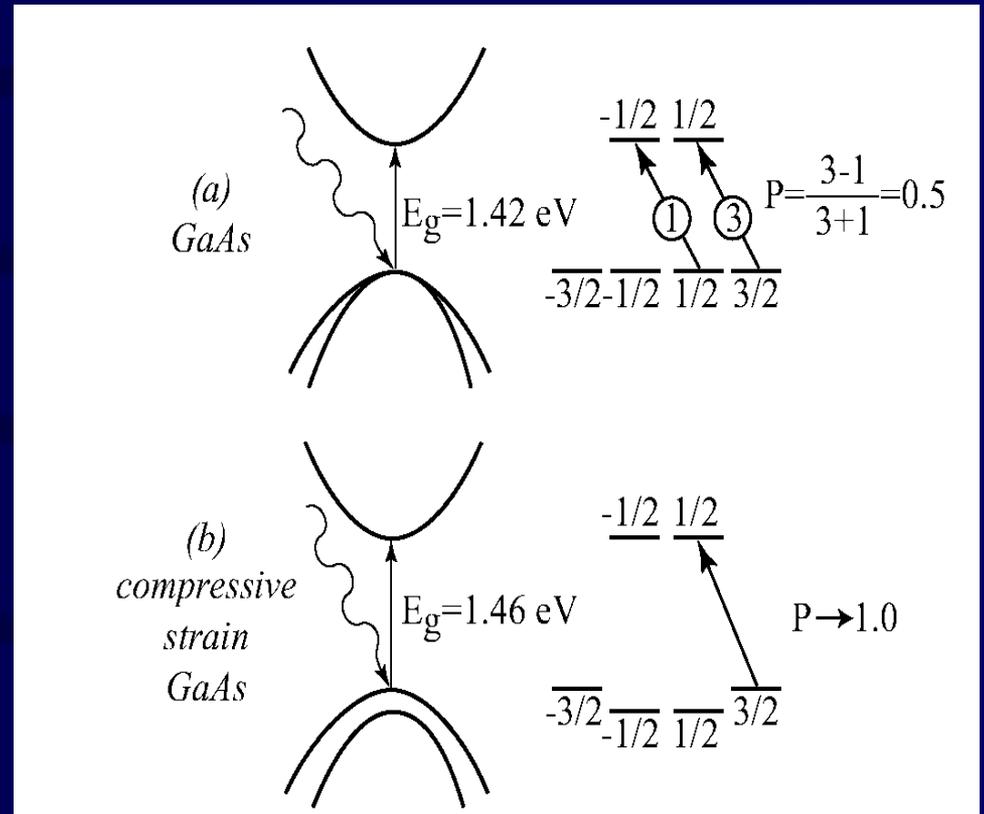
- *Application: Night vision / image intensifiers, highly sensitive photodetectors*
- *Application: Spin polarized emitter*
  - *Emission heavily favoring an "up" or "down" spin of electrons*
  - *Useful in some high energy physics experiments, spin polarized electron microscopy*

*Spin Polarized Emission (reflective mode)*



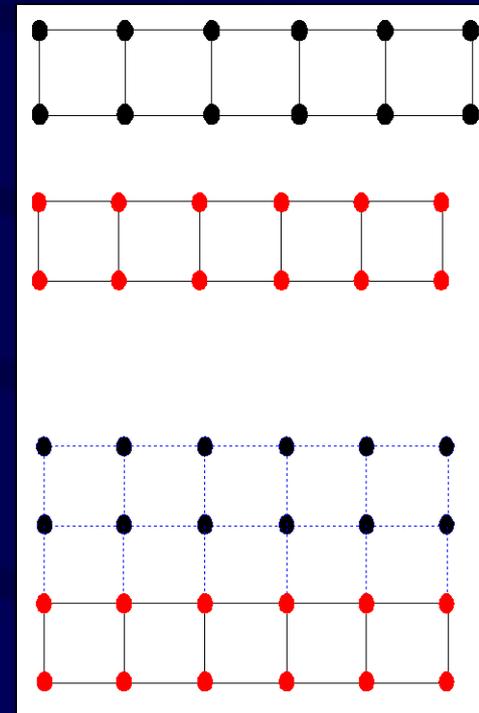
# Polarized Emitters

- Photocathode emission
  - Circularly polarized light
- Unstrained GaAs
  - 50% max polarization
- Compressively strained GaAs
  - lattice constant  $< 5.65 \text{ \AA}$
  - valence band splitting
  - $3/2 \rightarrow 1/2$  transition favored
  - 100% max polarization



# Creating Strained GaAs Layers

- Heteroepitaxy
- New layers will form based on previous lattice
- Compressive strain
  - Growth on lattice with smaller lattice constant
- Larger difference in lattice size  
————— increased strain force



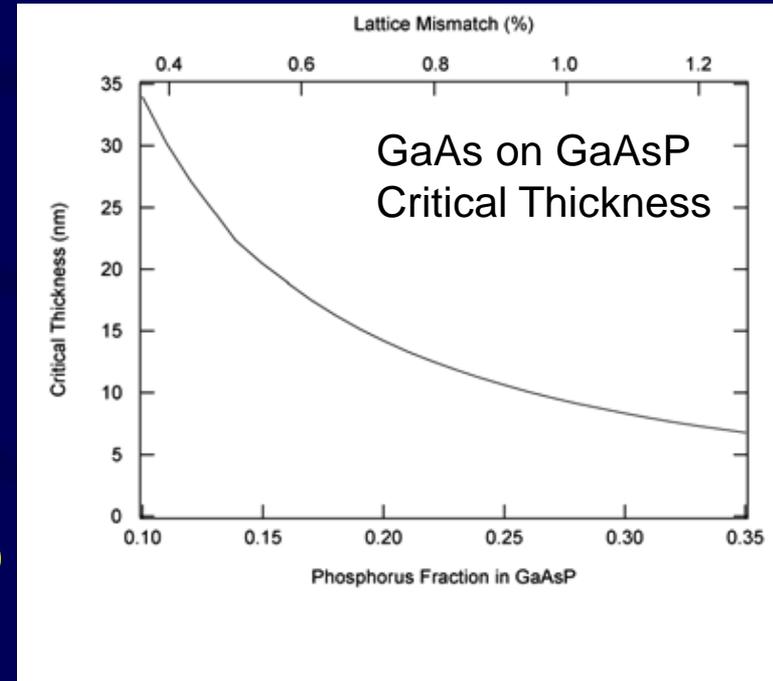
GaAs 5.65 Å

GaAs<sub>0.64</sub>P<sub>0.36</sub> 5.58 Å

Compressively strained  
GaAs on GaAs<sub>0.64</sub>P<sub>0.36</sub>  
lattice constant 5.58 Å

# Limits to Strained Layers: Critical Thickness

- Strain forces increase with thickness
- Strain reaches threshold, lattice relaxes
- “Critical Thickness”
  - Layer thickness where relaxation occurs
  - Relaxed lattice- bulk crystal state
  - Thickness inversely proportional to strain (difference in lattice constant)
- Misfit dislocations created
  - Scattering, absorption of photons
  - Non-uniformities

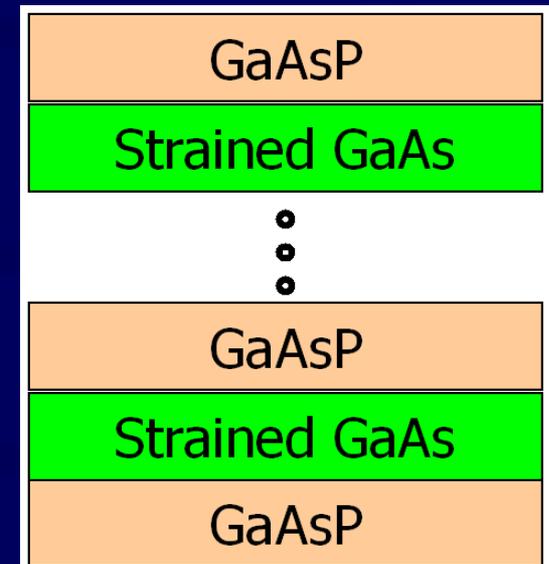


# Photocathode Polarized Emitters

- Device Considerations
  - Strained GaAs layer
    - Highly p-type doped
    - Thick to provide enough emission current
  - Structure Growth
    - Uniform
    - Excellent crystallinity
  - Substrate for epitaxy
    - High quality
    - Robust

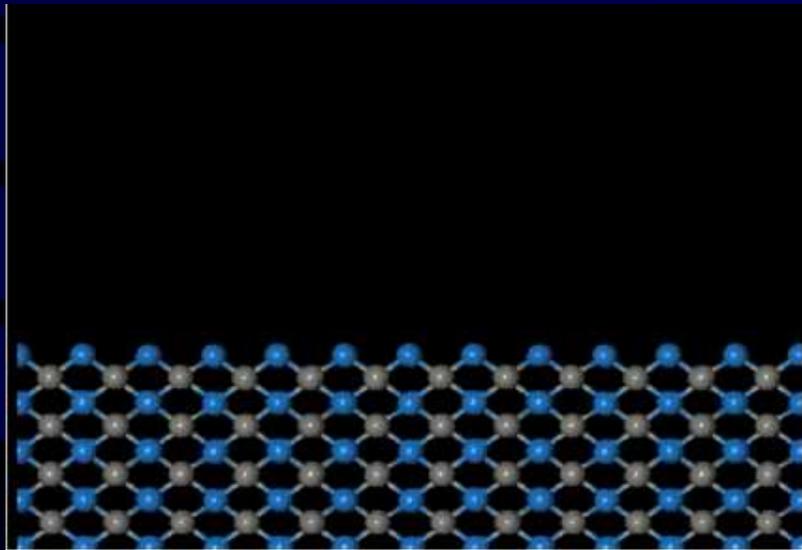
# Strained Superlattice Photocathode

- Strained GaAs on  $\text{GaAs}_x\text{P}_{1-x}$
- Multiple GaAs layers sandwiched by  $\text{GaAs}_x\text{P}_{1-x}$ 
  - Each GaAs layer below critical thickness
  - Multiple GaAs layers to provide thick overall active volume for electron emission
  - Superlattice- repetition of thin layers
- MBE for epitaxy
  - Thin layers ( $< 50 \text{ \AA}$ )
  - Utilizes phosphorus
  - Abrupt, uniform interfaces

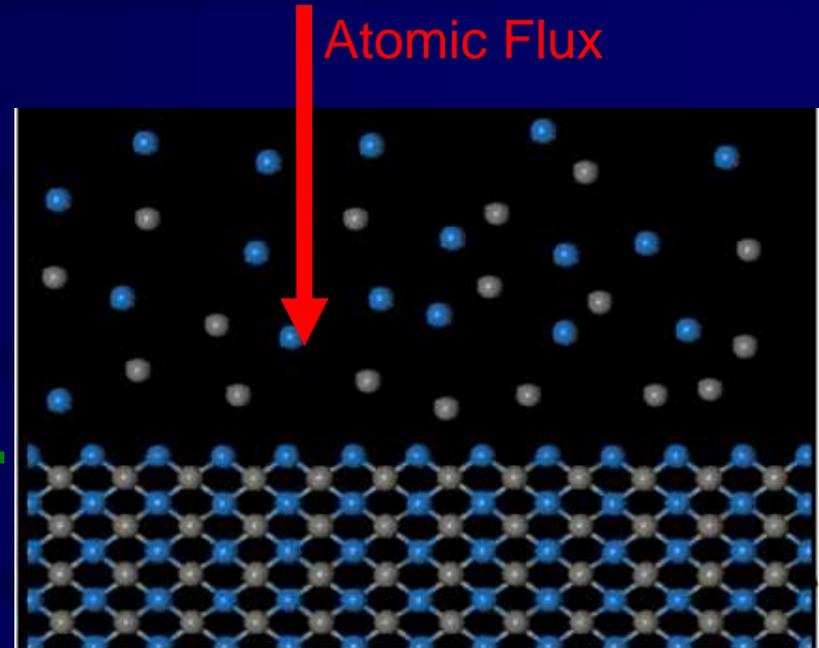


# Epitaxy

Growth of thin film crystalline material where crystallinity is preserved, "single crystal"

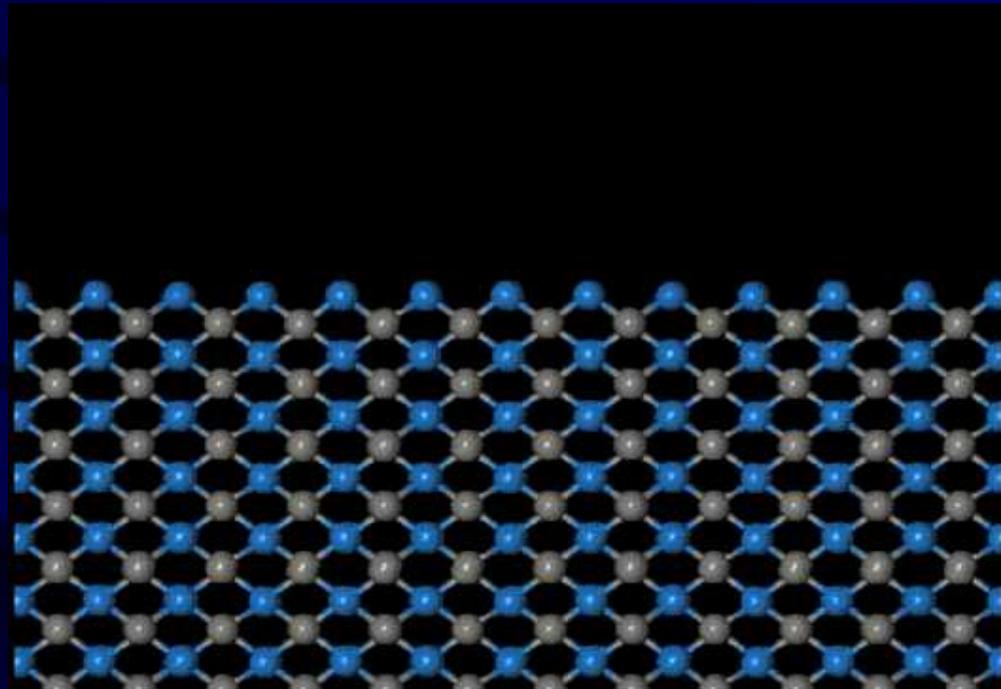


Bare (100) III-V surface,  
such as GaAs



Deposition of crystal source  
material (e.g. Ga, As atoms)

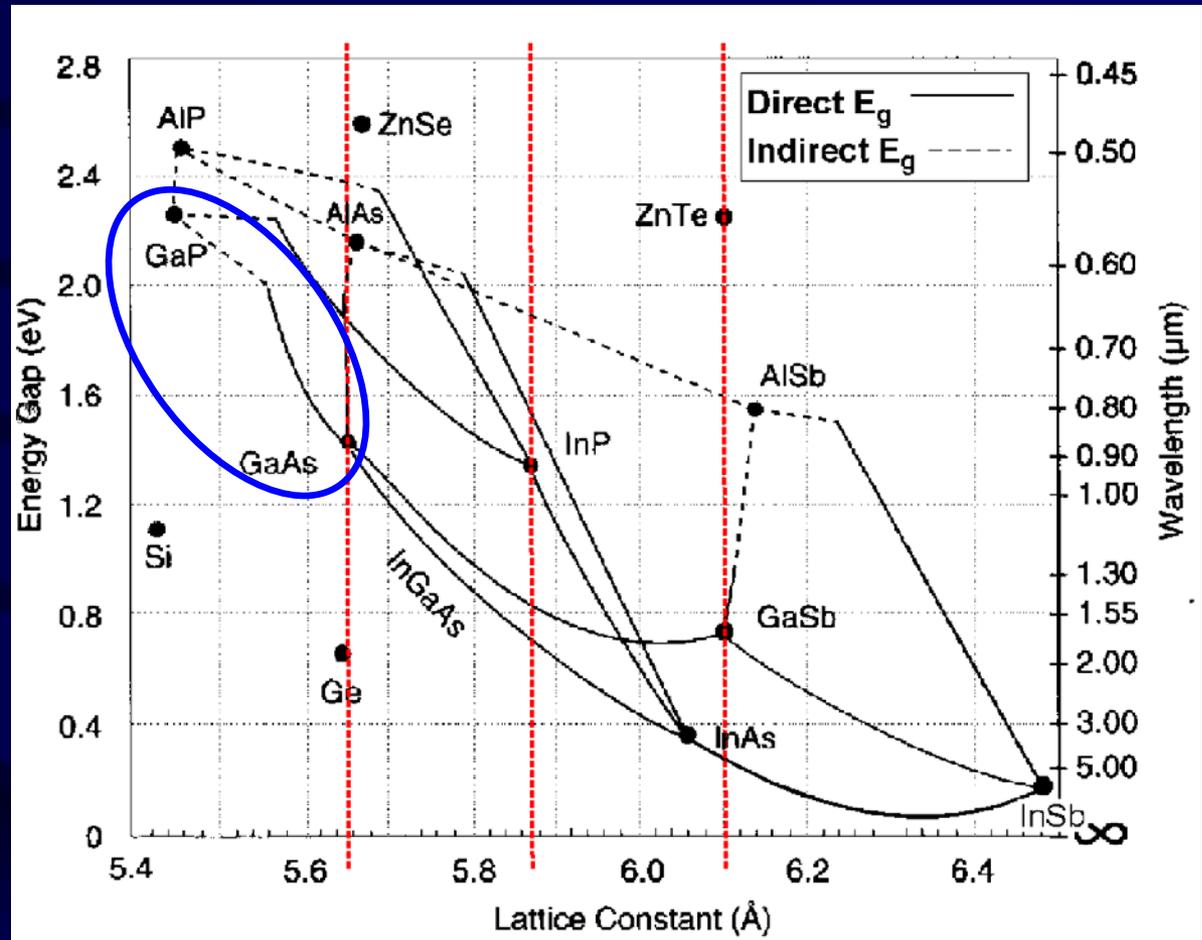
Result: Newly grown thin film, lattice structure maintained



Starting surface

# III-V Compound Semiconductors

III	IV	V	VI	VII	VIII
					He
B	C	N	O	F	Ne
Al	Si	P	S	Cl	Ar
Ga	Ge	As	Se	Br	Kr
In	Sn	Sb	Te	I	Xe
Tl	Pb	Bi	Po	At	Rn

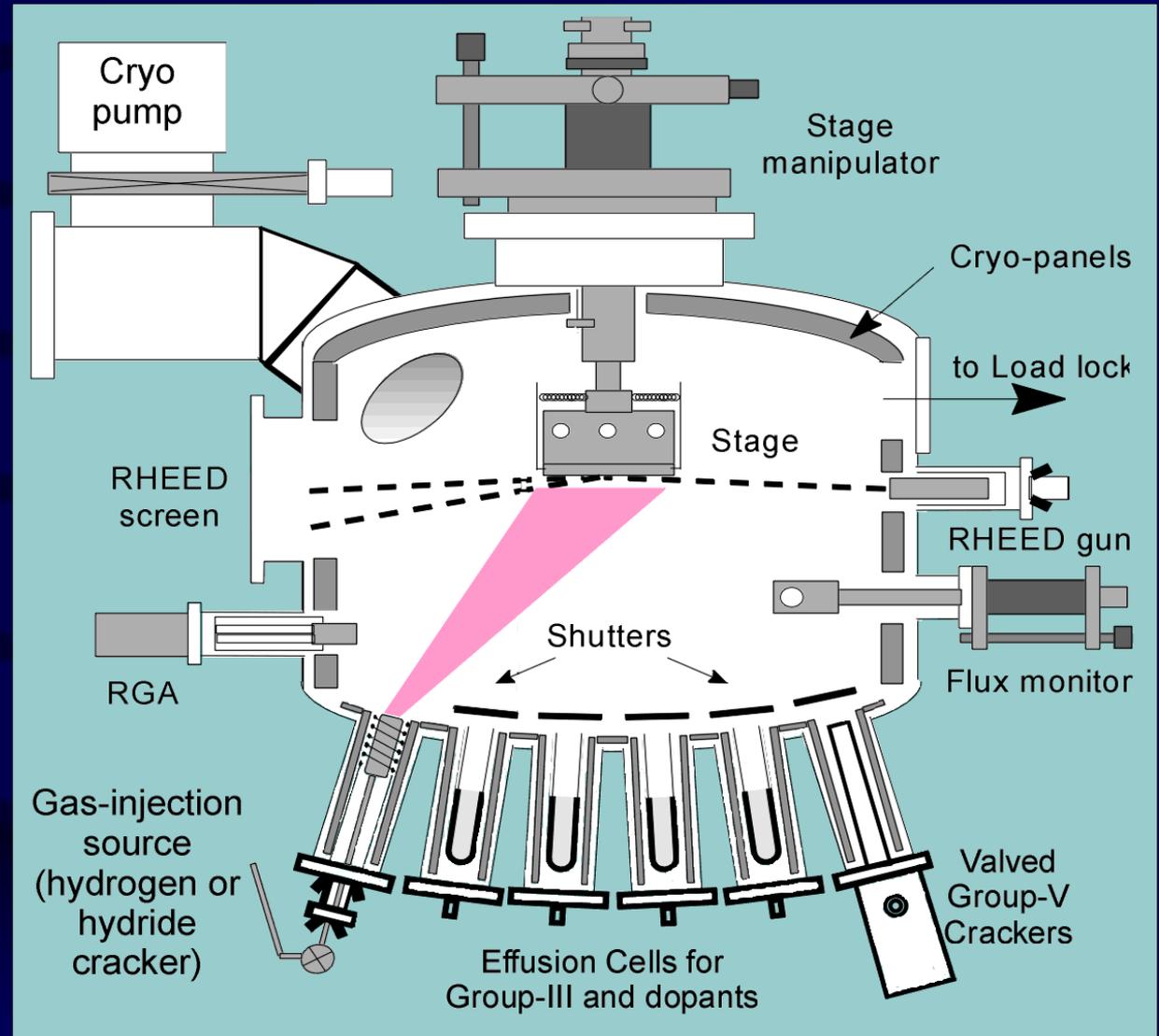


# Molecular Beam Epitaxy (MBE)

- Growth in high vacuum chamber
  - Ultimate vacuum  $< 10^{-10}$  torr
  - Pressure during growth  $< 10^{-6}$  torr
- Elemental source material
  - High purity Ga, In, Al, As, P, Sb (99.9999%)
  - Sources individually evaporated in high temperature cells
- In situ monitoring, calibration
  - Probing of surface structure during growth
  - Real time feedback of growth rate

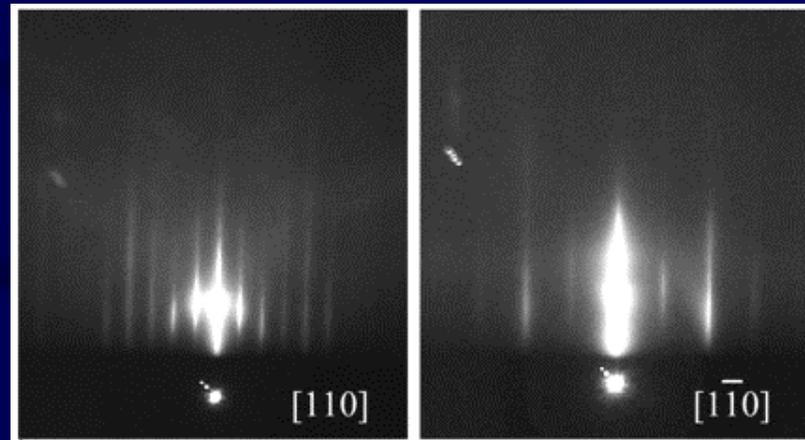
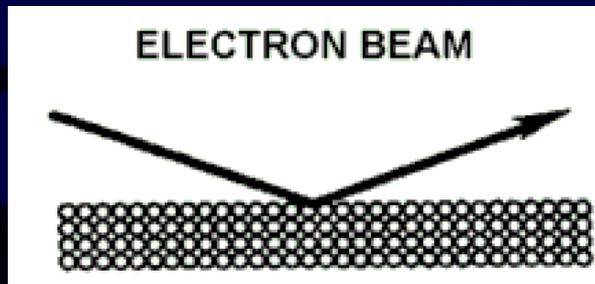
# Molecular Beam Epitaxy

Growth Apparatus:



# MBE- In Situ Surface Analysis

- Reflection High Energy Electron Diffraction (RHEED)
- High energy (5-10 keV) electron beam
- Shallow angle of incidence
- Beam reconstruction on phosphor screen



RHEED image of GaAs (100) surface

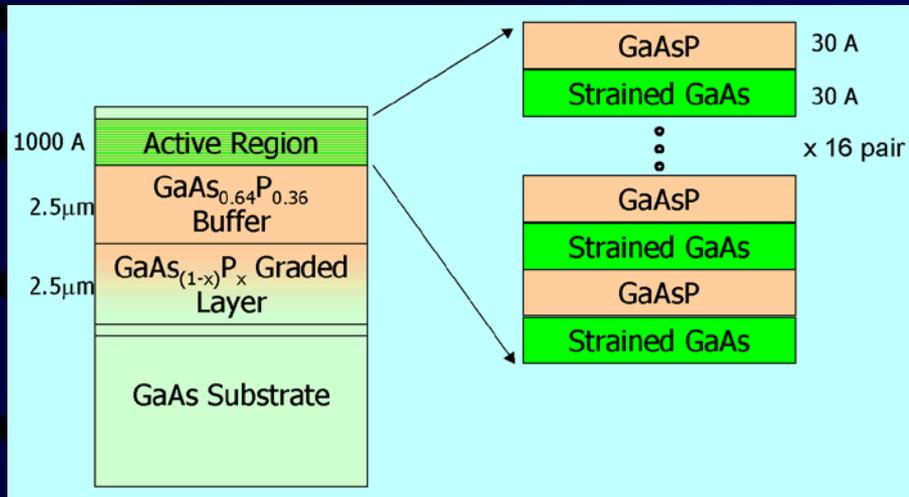
# MBE System Photo



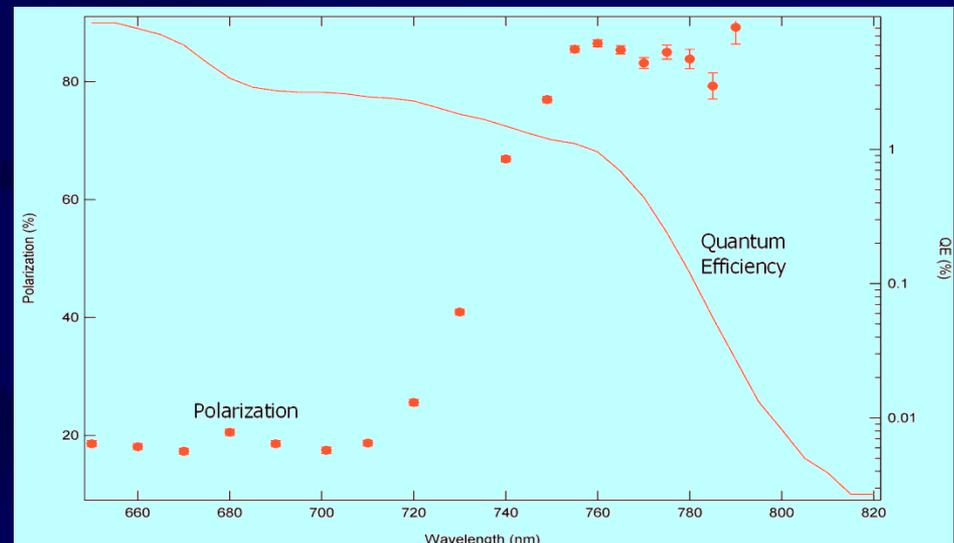
# MBE- Summary

- Ultra high vacuum, high purity layers
- No chemical byproducts created at growth surface
- High lateral uniformity (< 1% deviation)
- Growth rates 0.1-10 micron/hr
- High control of composition and thickness
- Lower growth temperatures than MOCVD
- In situ monitoring and feedback
- Mature production technology

# MBE Grown GaAsP SL

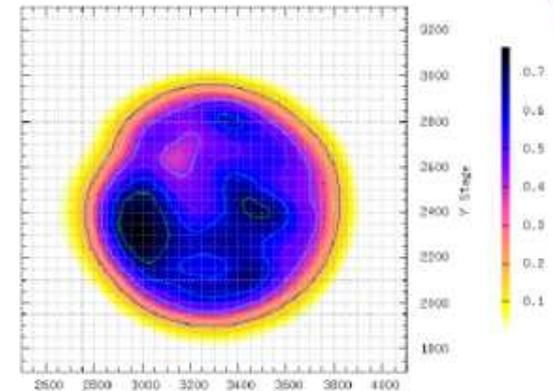
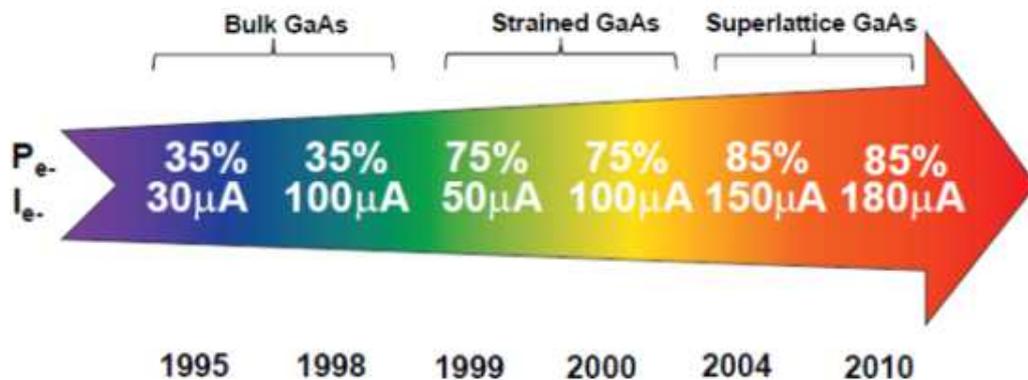


- greater than 1% QE
- achieved 86% polarization
- material specific spin depolarization mechanism



US Dept. of Energy SBIR Phase I and II  
contract #DE-FG02-01ER83332,  
collaboration with SLAC

# Jlab - ILC High Current Polarized Electron Source



R. Suleiman et al., PAC'11, New York (NJ, USA), March 28 - April 1, 2011



Parameter	Value
Laser Rep Rate	1500 MHz
Laser Pulelength	50 ps
Laser Wavelength	780 nm
Laser Spot Size	350 $\mu\text{m}$ FWHM
High-Pol Photocathode	SSL GaAs/GaAsP
Gun Voltage	200 kV DC
<b>CW Beam Current</b>	<b>4 mA</b>
<b>Run Duration</b>	<b>1.4 hr</b>
Extracted Charge	20 C
1/e Charge Lifetime	85 C
Bunch charge	2.7 pC
Peak current	53 mA
Current density	55 A/cm <sup>2</sup>

# MBE Grown GaAsP SL for Polarized Photocathode Emitters

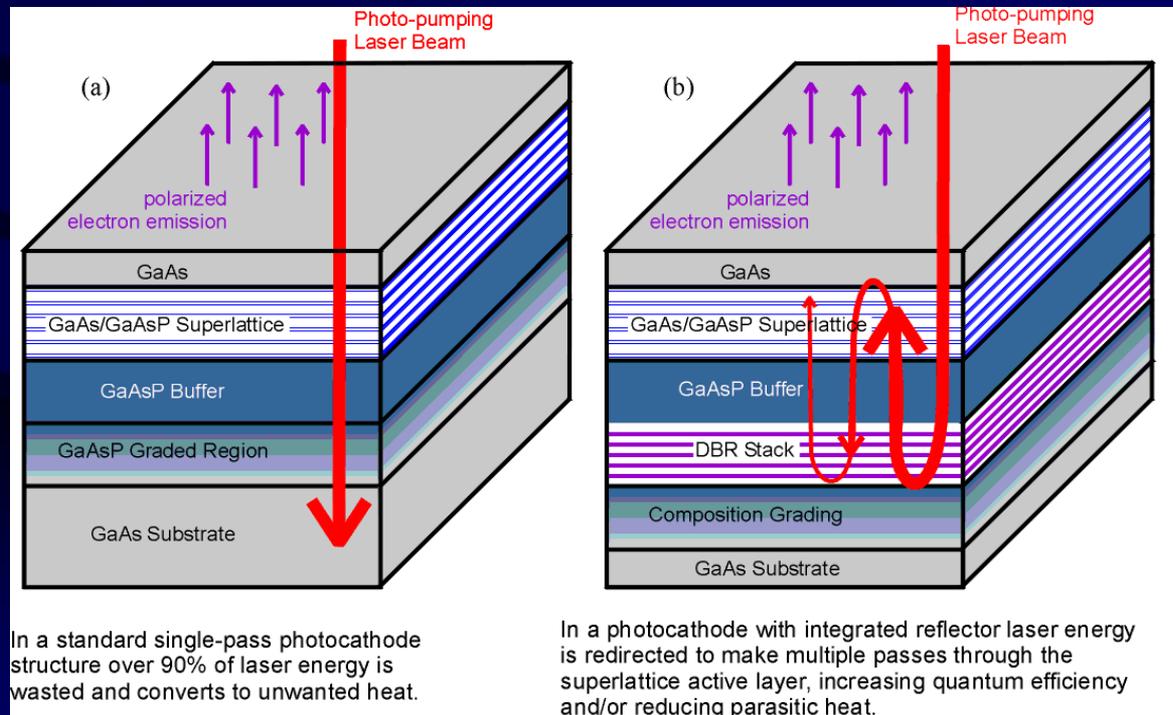
- SVT supplied photocathodes with > 80% polarization
  - CEBAF/JLab, SLAC, Mainz Microtron and Bonn/ELSA
- SVT first company to supply Arsenic capped devices
  - As-capping protects surface from atmospheric contamination
  - Arsenic removed in vacuum before activation
  - Improved success rate of installed photocathodes

# Improving Polarized Photocathode Emitters

- Increased polarization?
  - Material quality
  - Alternative material systems
- Increased quantum efficiency (output current)?
  - QE ratio of incident photons to extracted polarized electrons
  - Reduce depolarizing mechanisms (material quality)
  - Only a small percentage of laser light is absorbed by superlattice active layer
  - Increase laser power -> more waste heat
  - Increase QE by maximizing pertinent photon absorption

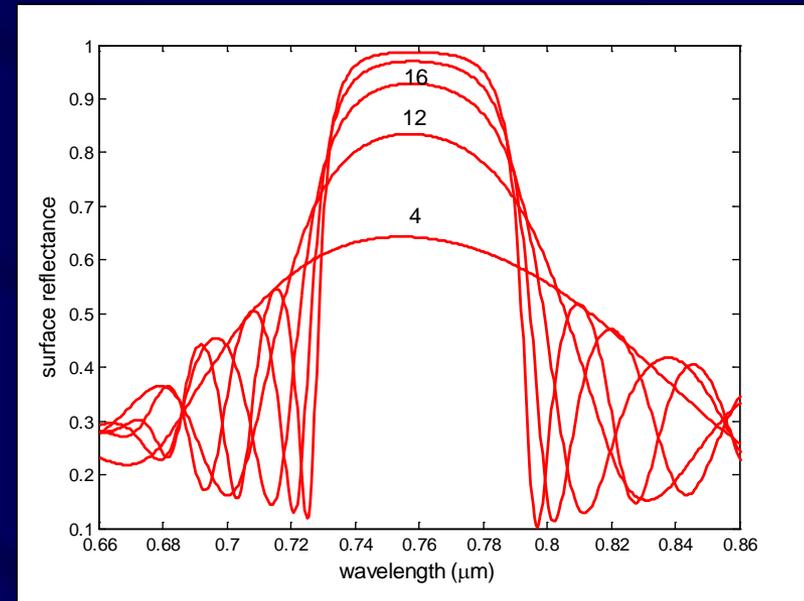
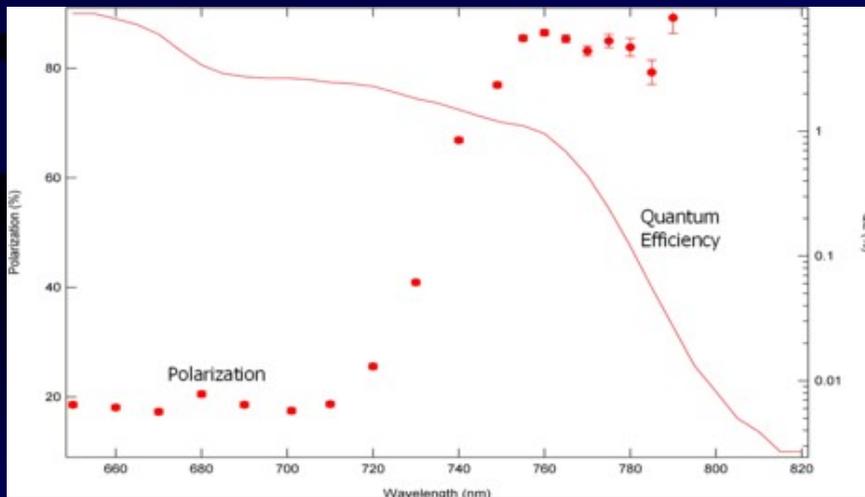
# Improving Polarized Photocathode Emitters

- “One-pass” status quo design (left), less than 10% photon absorption in active area
- Add mirror to structure to create multiple reflections of excitation beam



# Combining DBR Mirror with Photocathode

- Distributed Bragg Reflector (DBR)
  - Pairs of layers with differing optical indexes of refraction
  - Layer thickness dependent on desired wavelength for reflection
  - Layer material must be compatible with substrate and active layer
  - Layer material must be transparent to target wavelength

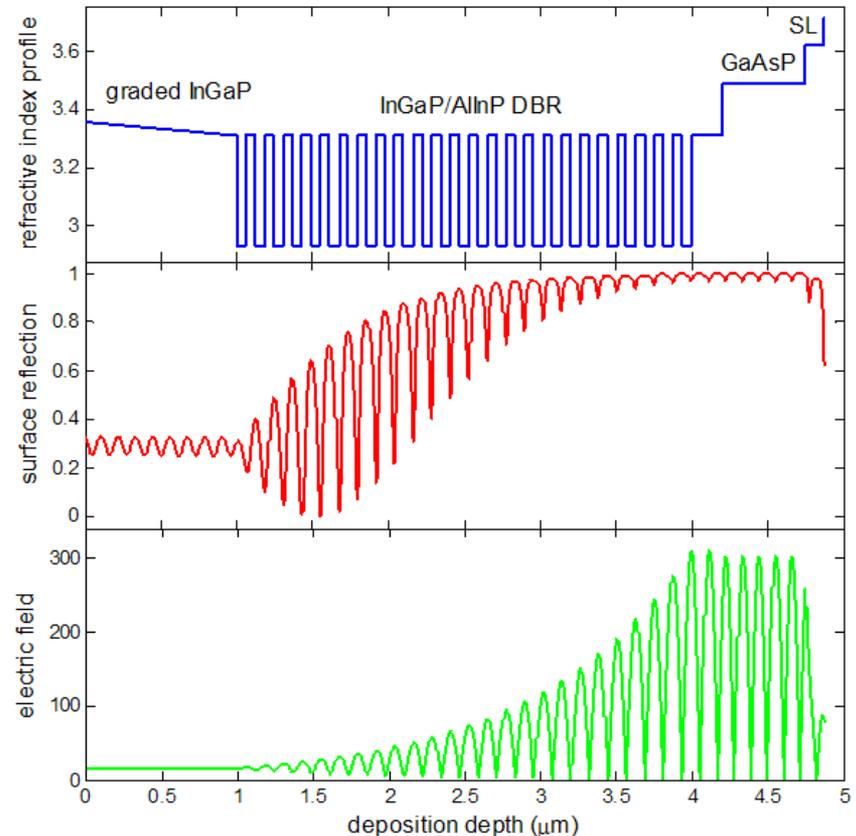


# Modeling of DBR Mirror with Photocathode

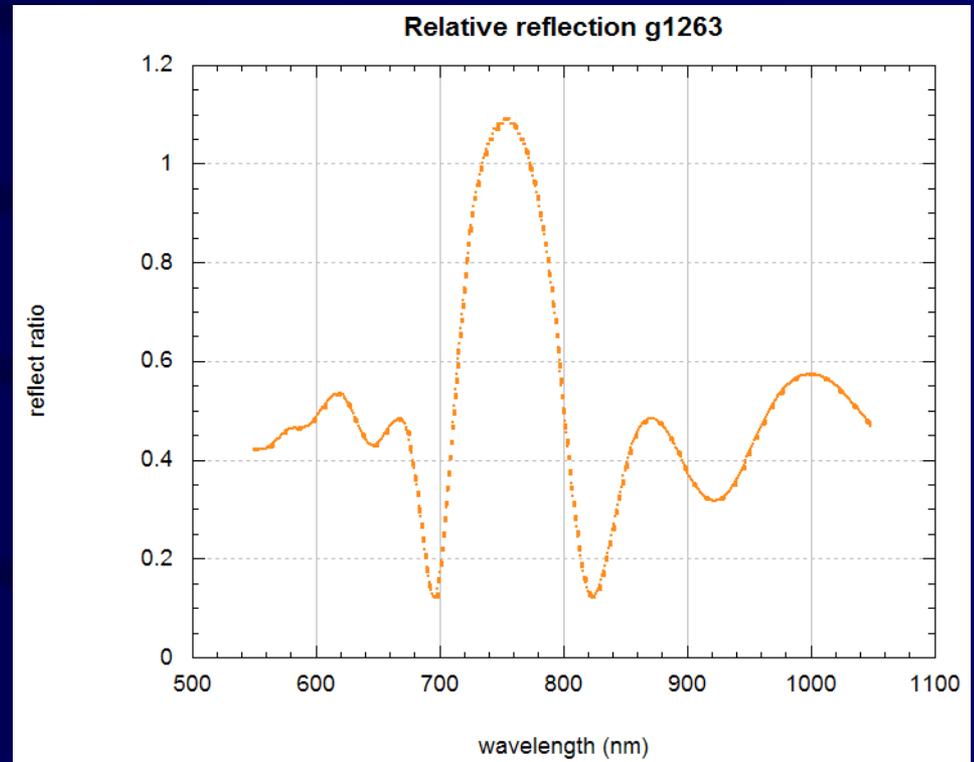
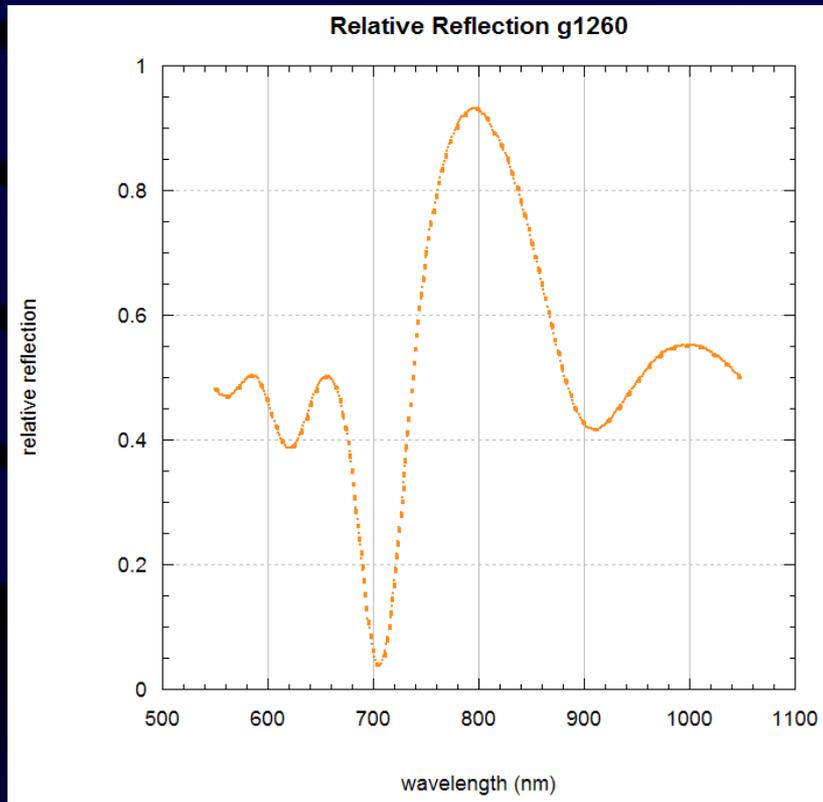
Refractive index and thickness of materials in another DBR with Fabry-Perot cavity at 760 nm.

	AlInP	InGaP	InGaP buffer	GaAsP	GaAs/GaAsP SL	GaAs
n	2.9356	3.3102	3.3102	3.4888	3.6192+0.0226i	3.712+0.095i
d (nm)	64.72	57.40	145	550	120	5

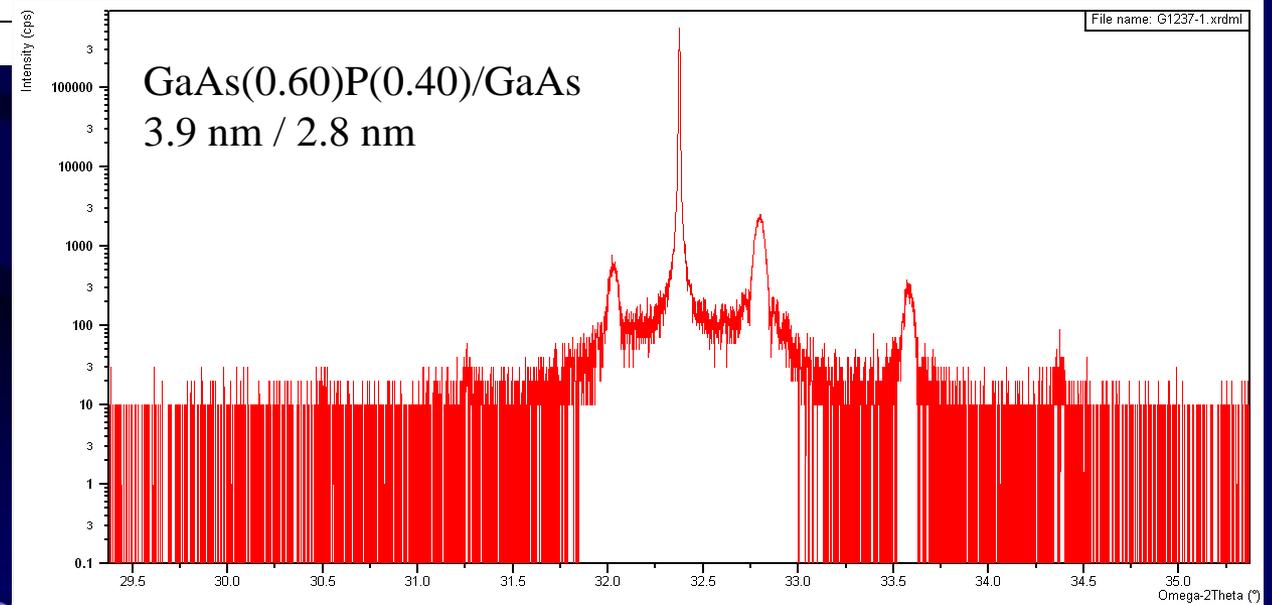
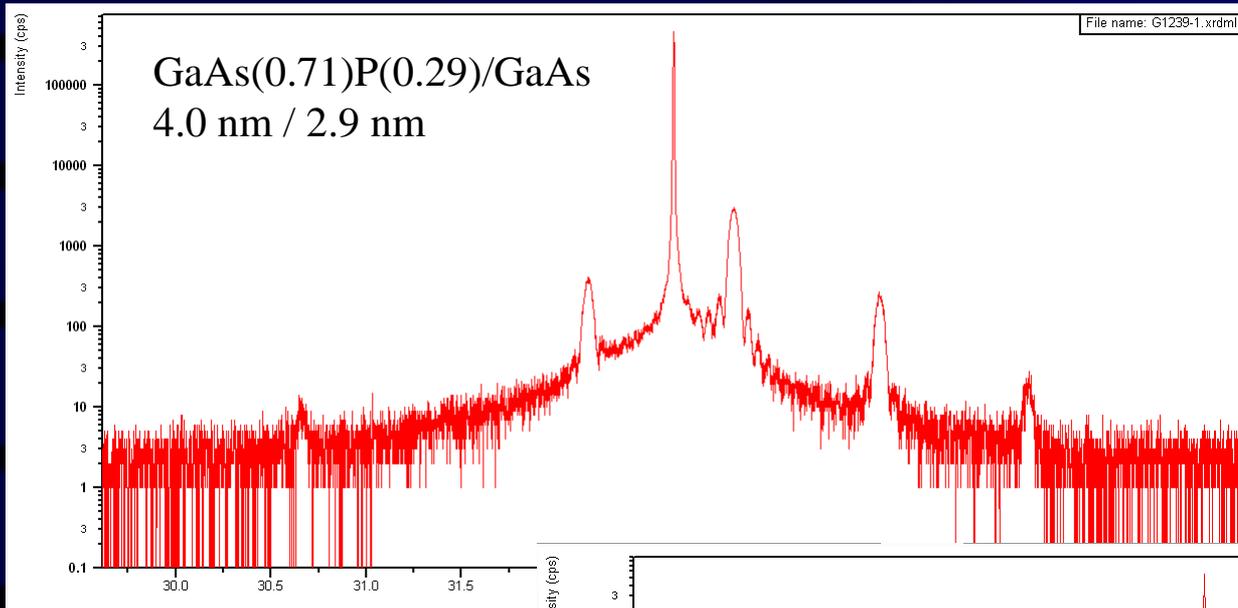
- DBR and surface reflection create optical Fabry-Perot cavity
- Photons repeatedly bounce between DBR and surface
- E-field of incident light strongest in active area near ejection surface



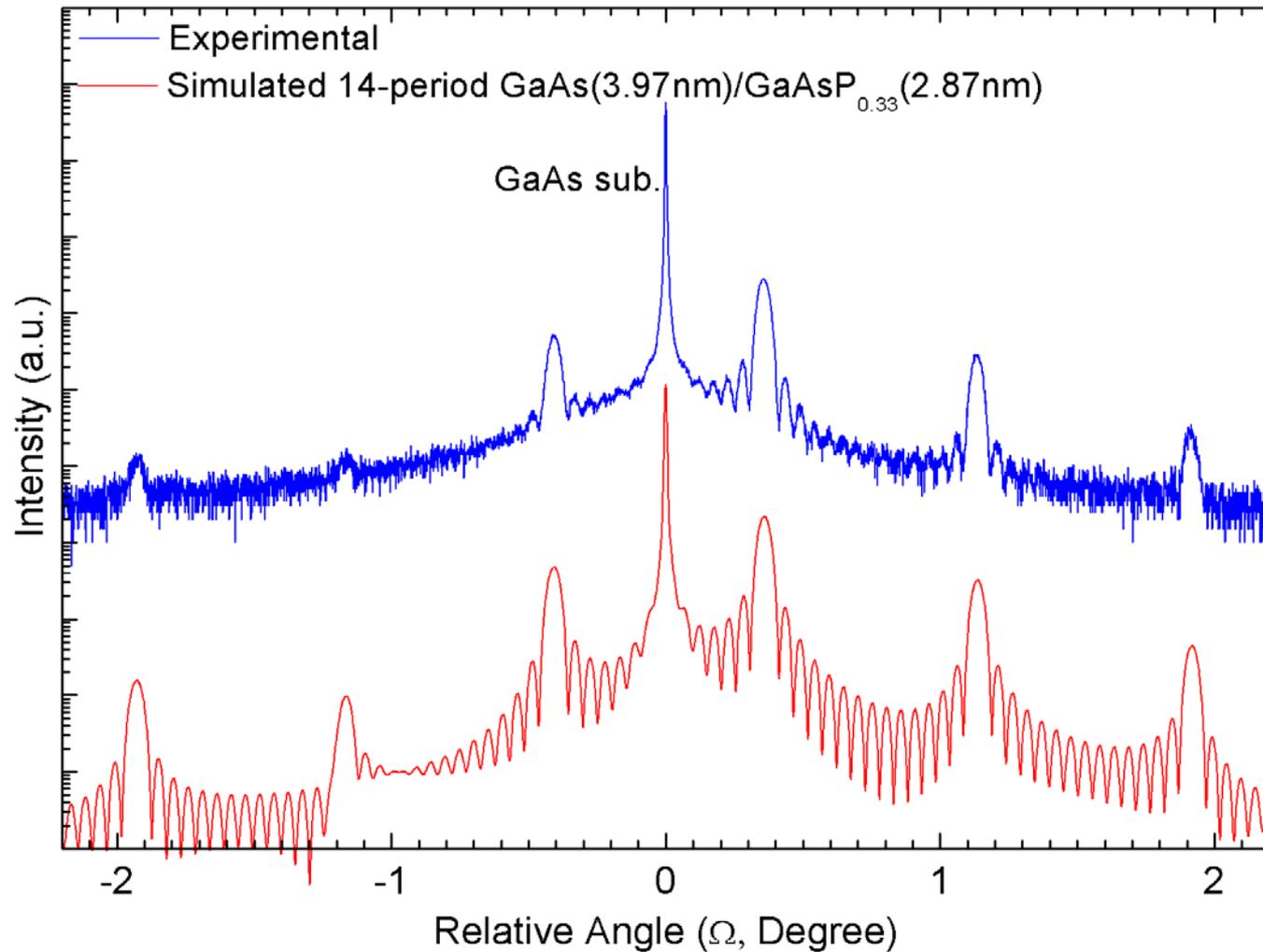
# Growth and Measurement of DBR Mirror



# Calibration of GaAs(x)P(1-x)/GaAs Superlattice



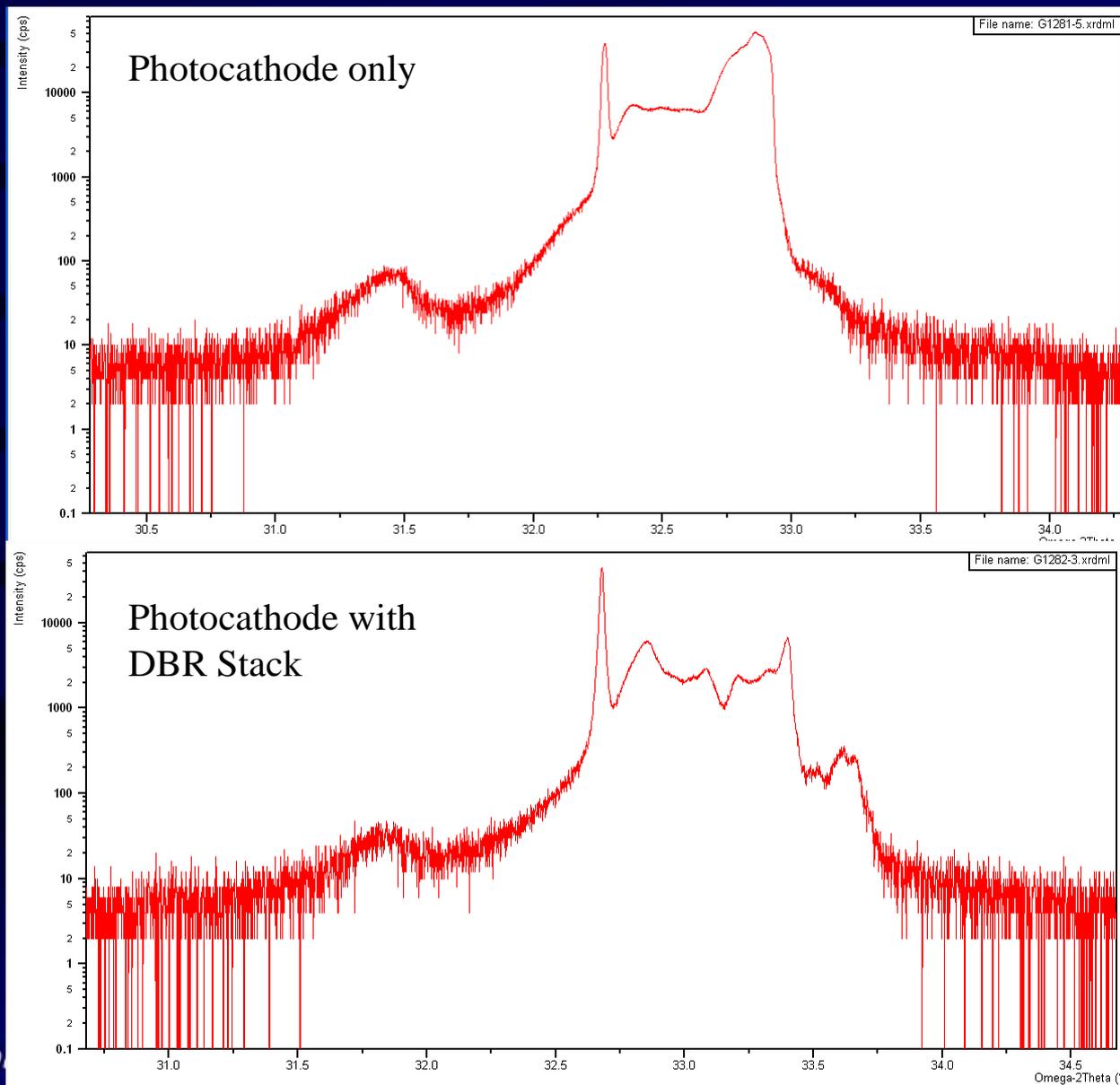
# Calibration of GaAs(x)P(1-x)/GaAs Superlattice



# Structure of DBR Photocathode

emitter	GaAs	5nm
superlattice	GaAs/GaAs <sub>0.64</sub> P <sub>0.36</sub> SL	3.8/2.9 nm x 14 pair
buffer	GaAs <sub>0.64</sub> P <sub>0.36</sub> SL	2.5 um
DBR stack	GaAs <sub>0.64</sub> P <sub>0.36</sub> /AlGaAsP	1.4 um
grading layer	GaAsP composition grade	
	GaAs buffer	
	GaAs substrate	

# X-Ray of Grown DBR Photocathodes



# DBR Photocathodes Status

- Growth of two samples completed
  - One polarized photocathode structure only (control)
  - One polarized photocathode structure with DBR stack
- Awaiting polarization and QE data
- Optically measure DBR reflection of sample, compare with QE data
- Modify structure and produce new samples if needed

# Conclusion

- Photocathodes with polarized emission
- Increased polarization and current -> faster collection of data
- GaAsP/GaAs SL structure already proven and in use
- Reflector integrated into photocathode
- Laser light inside Fabry-Perot cavity for increased absorption
- Modeling predicts up to an order of magnitude absorption increase
- Control and experimental samples grown, awaiting polarization and QE measurement.